

LTCC ultra high isostatic pressure sensors

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Outline

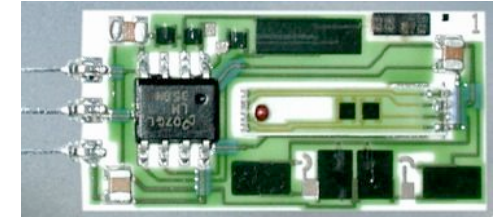
1. Introduction - **LTCC & hydrostatic sensors**
2. Sensor design & fabrication - **LTCC process & package**
3. Modelling - **expected sensor performance**
4. Results - **sensor performance & limitations**
5. Conclusions & outlook

1. Introduction

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1. Thick-film piezoresistive sensors

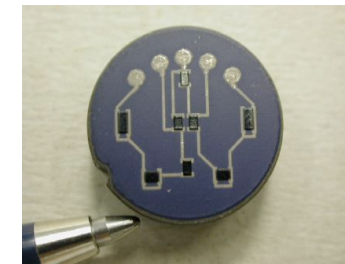
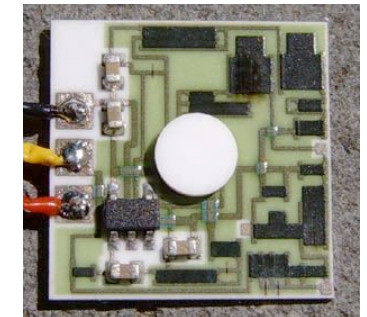
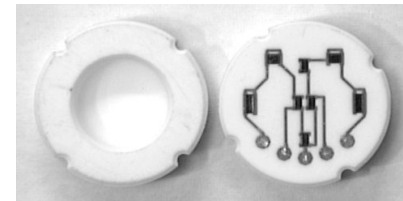
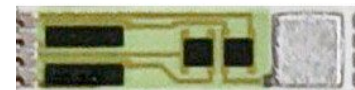
- Force sensor 100 ... 2'000 mN
 - Alumina cantilever
 - LTCC cantilever
- Force sensor 4 ... 200 N
- Pressure sensor (alumina)
- Pressure sensor (steel)



Top



Bottom

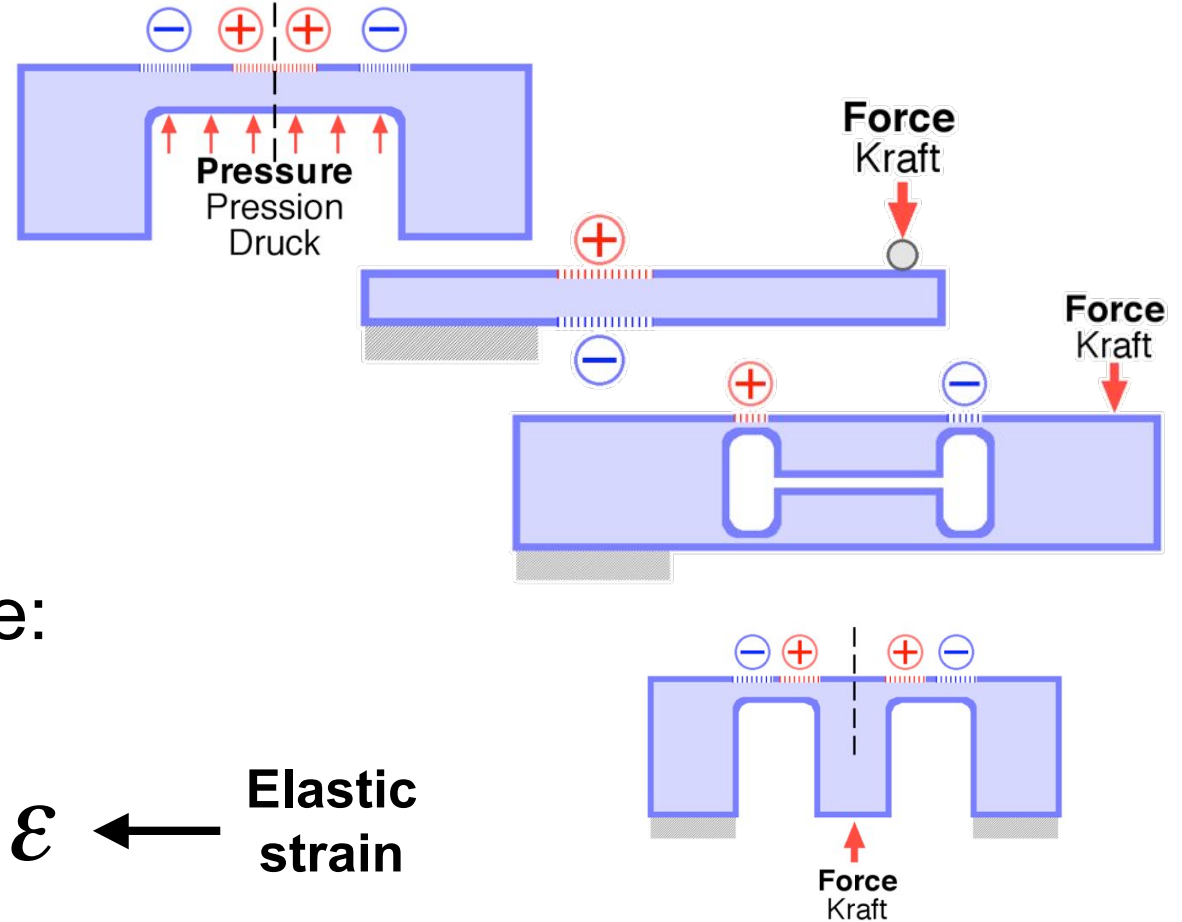


→ Principle: substrate bending

1. Piezoresistive sensors: bending

■ Typical structures

- Membrane
- Cantilever
- Parallelogram
- Button / bridge



■ Piezoresistive response:

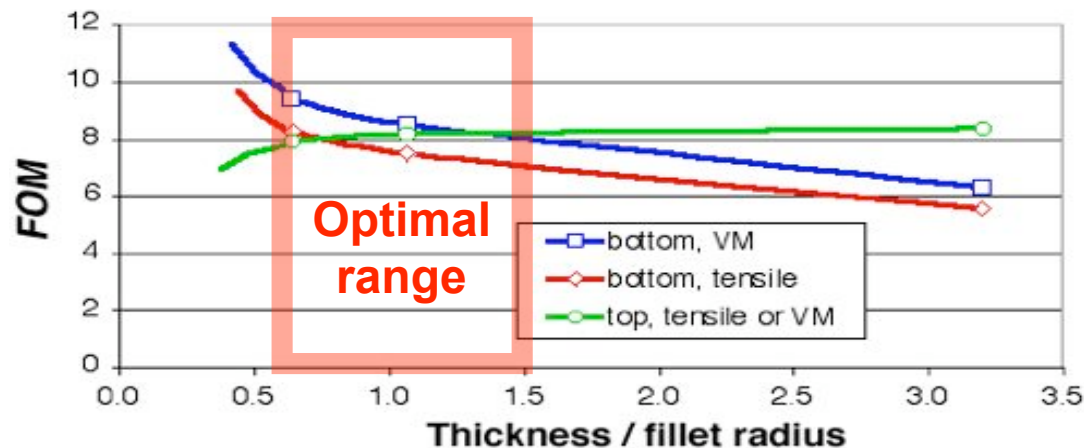
$$\frac{\Delta R}{R} = K \cdot \varepsilon$$

Relative resistance change \rightarrow $\frac{\Delta R}{R}$ \leftarrow Elastic strain ε

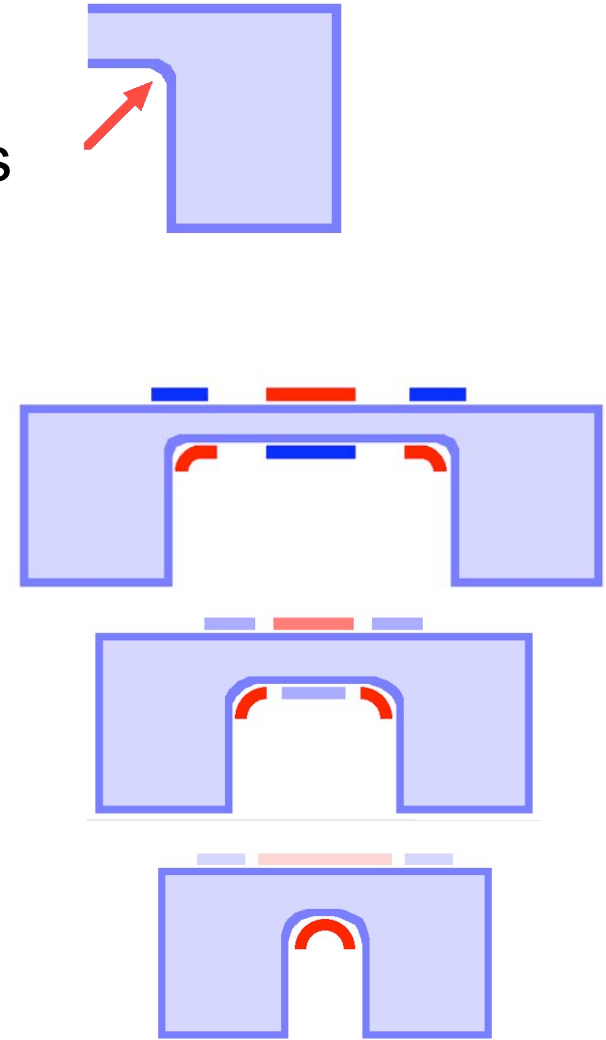
K \leftarrow Gauge factor

1. Sensors in bending: limitations

- Stress concentrations
 - Optimal: fillet radius \cong membrane thickness



- Pressure range
 - Low to medium: \cong membrane theory
 - High: lower signal
 - Very high: very low signal



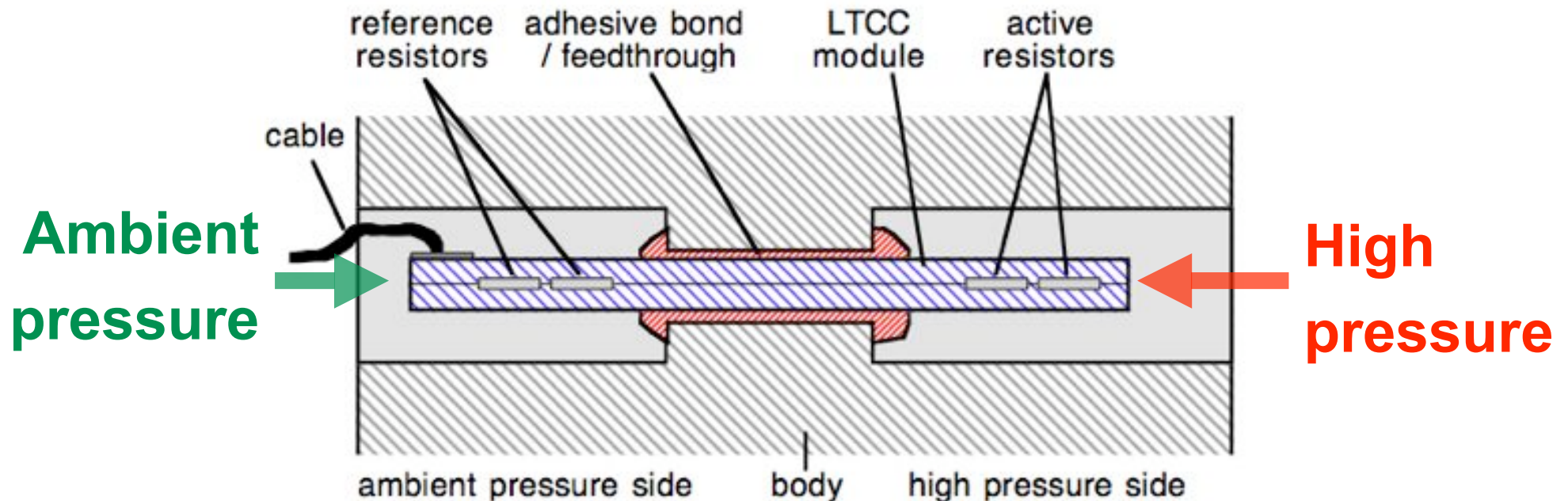
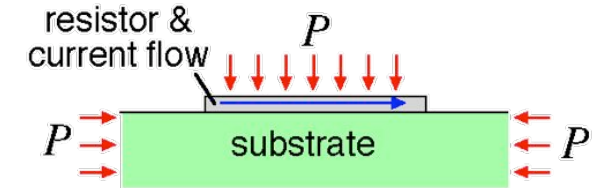
1. LTCC vs. alumina for sensors

Material	LTCC (DP 951)	Al ₂ O ₃ (96%)	Ratio
Minimal thickness [mm]	0.04	0.17	0.24
Short-term strength [MPa]	320	600	0.53
10 year strength [MPa]	110	270	0.41
Young's modulus [GPa]	110	320	0.34
Thermal conductivity [W/m]	3	25	0.12
Design strain [ppm]	1'000	800	1.25
Flexural sensitivity [kN ⁻¹]	5.68	0.11	53
Thermal resistance [K/W]	8'333	235	35

→ **LTCC more sensitive, but less strong: overall \cong**

1. Hydrostatic sensors

- Ceramics: limitations for tensile stresses
- In principle “unlimited” pressure allowed
→ **LTCC “hydrostatic” sensor concept:**

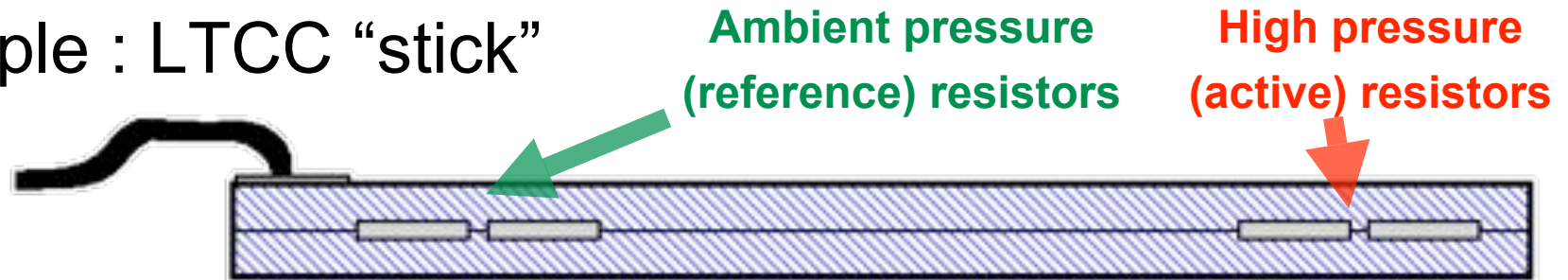


2. Sensor design & fabrication

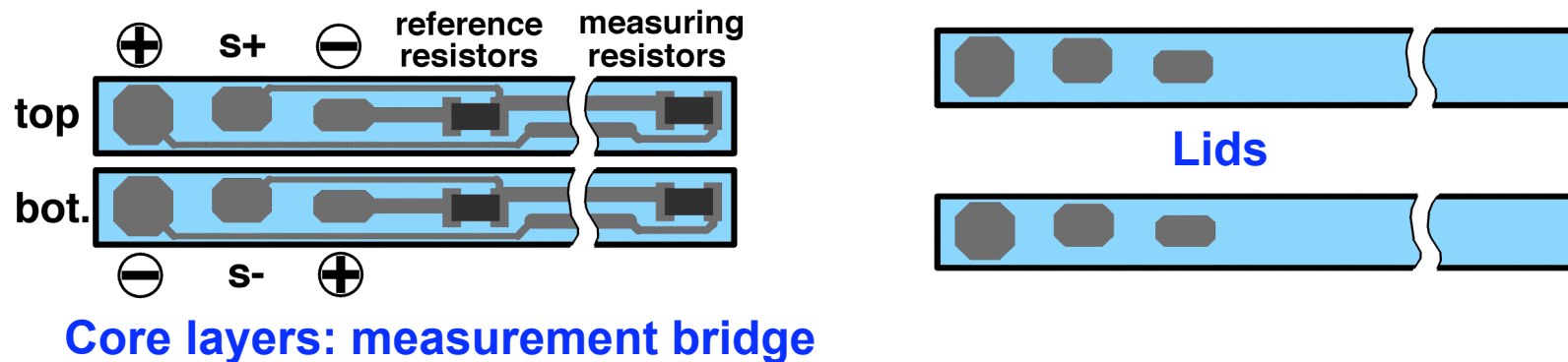
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5. Results - comparison with expectations
6. Conclusions & outlook

2. LTCC hydrostatic sensor module

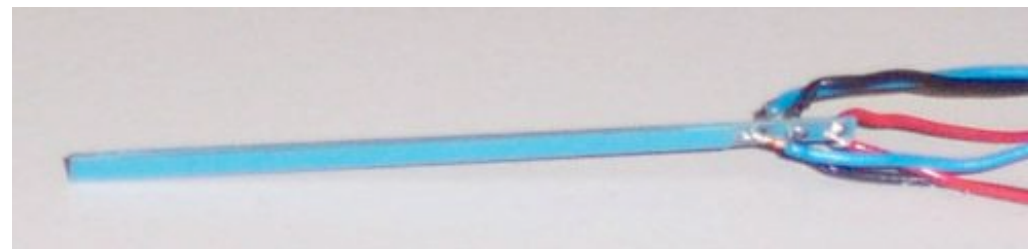
- Principle : LTCC “stick”



- Circuit: 4 LTCC layers (DP 951 & DP 2041)

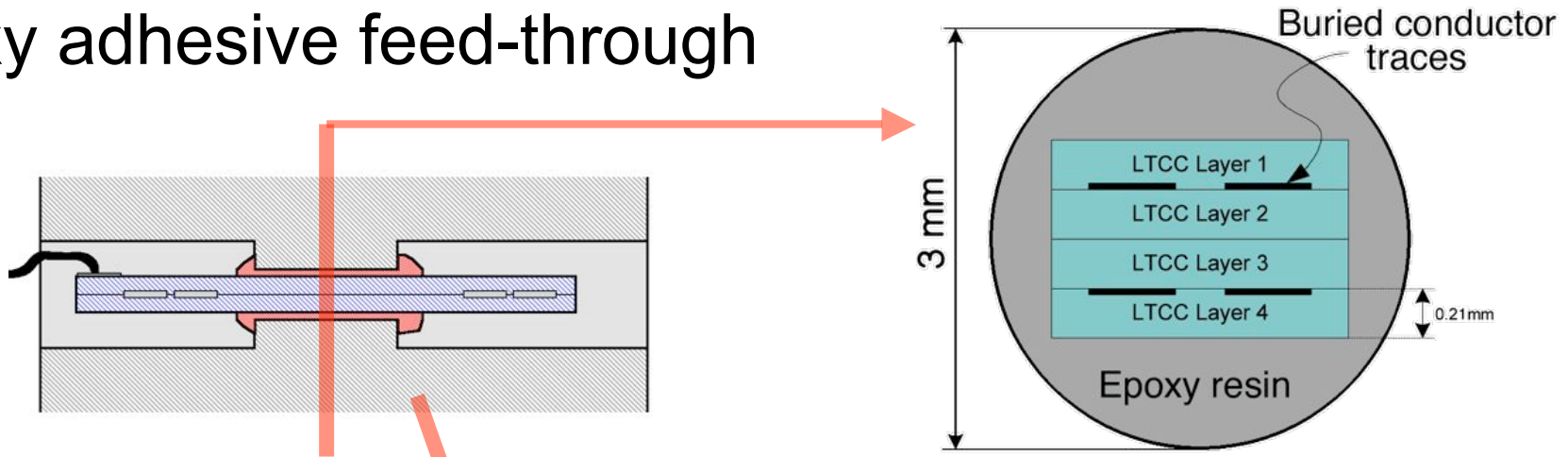


- Resulting module

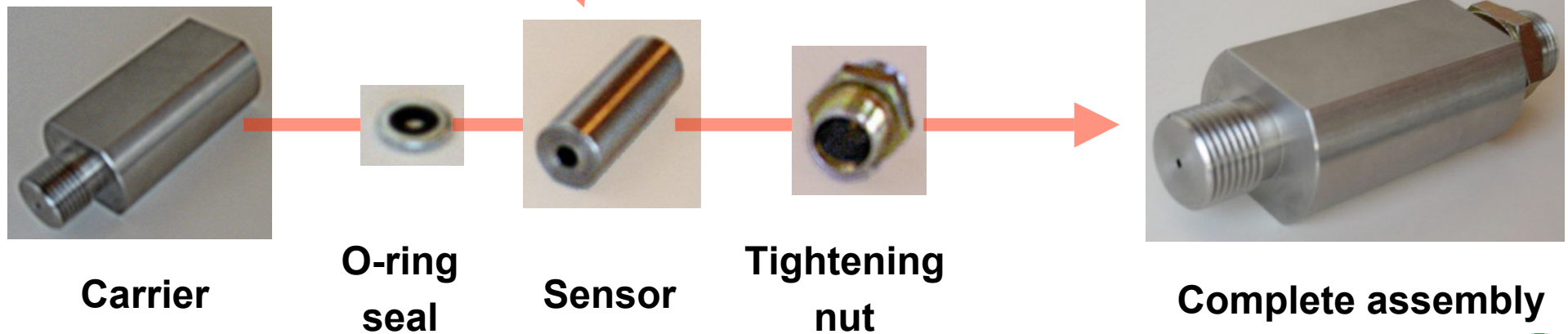


2. Sensor packaging & test jig

- Epoxy adhesive feed-through



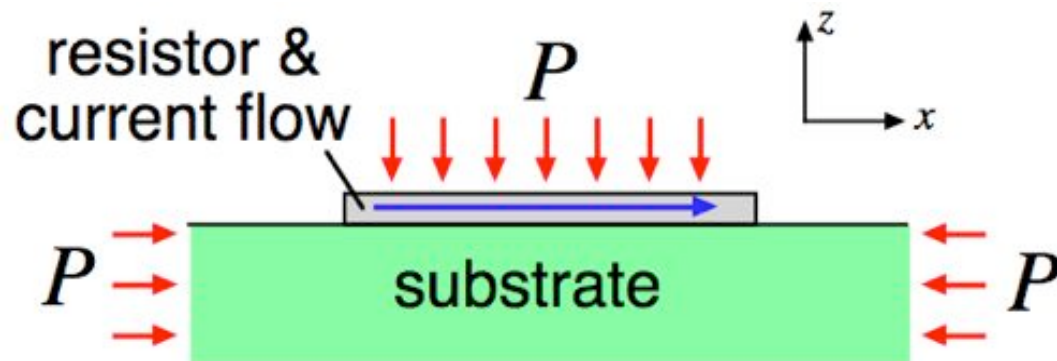
- Sensor test jig:



3. Modelling of sensor

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3. Resistor in hydrostatic pressure



Vertical:

- $E(\text{resistor}) \cong 70 \text{ GPa}$

Horizontal

- $E(\text{LTCC}) \cong 110 \text{ GPa}$
- $E(\text{Al}_2\text{O}_3) \cong 320 \text{ GPa}$

→ **LTCC advantages:**

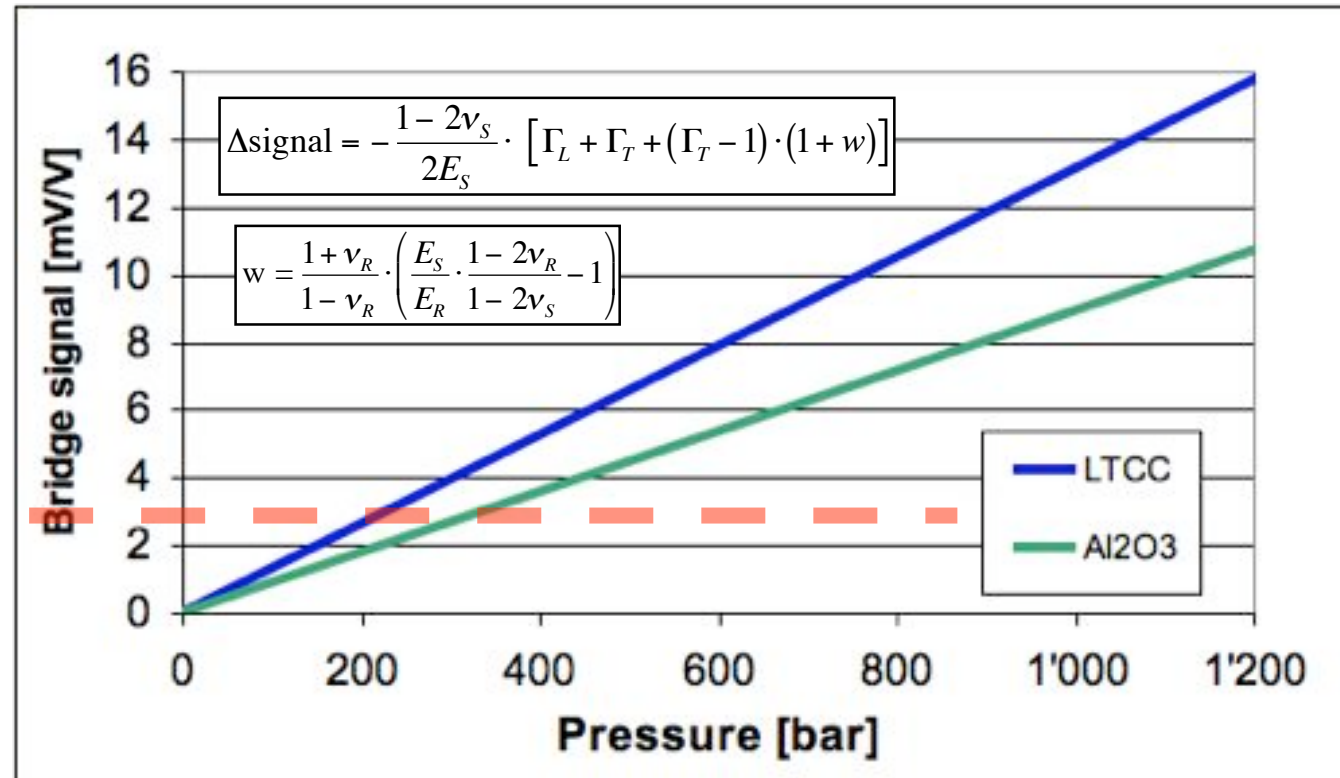
- Higher signal
- More isostatic stress (smaller E difference)
- Easy hermetic sealing (buried resistors)

3. Expected response

Includes 50%
reduction due to
half-bridge
design

3 mV/V

LTCC : Al₂O₃
≅ 3:2



- Very high achievable signal
- In theory limited by packaging only (feed-through)

4. Results

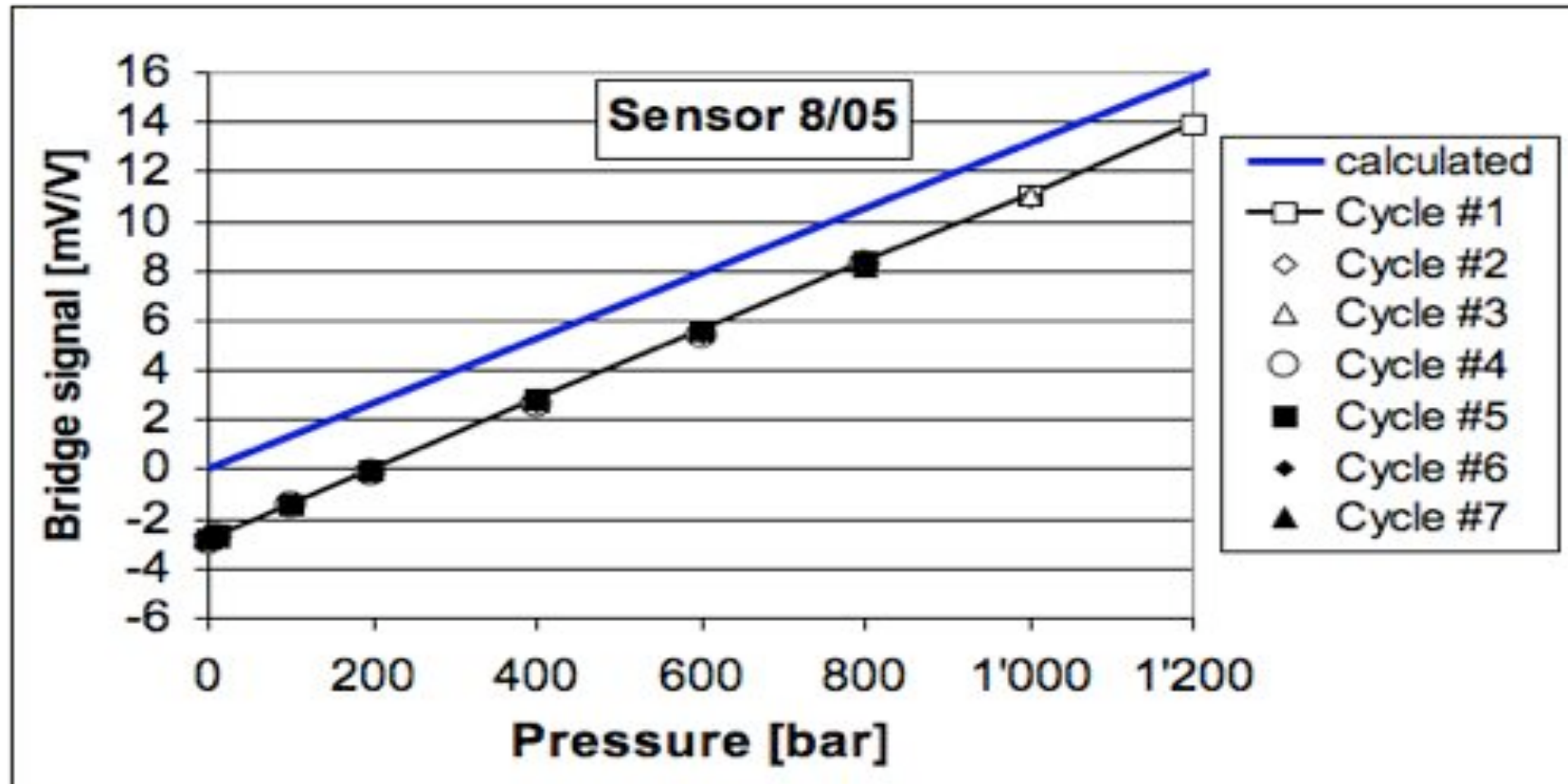
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4. Resistor & bridge offset values

Type	Co-fired buried	Co-fired open	(nominal)
Resistance	24 kΩ ± 6%	3.6 kΩ ± 6%	(10 kΩ)
Offset	7 ± 21 mV/V	78 ± 33 mV/V	(0)

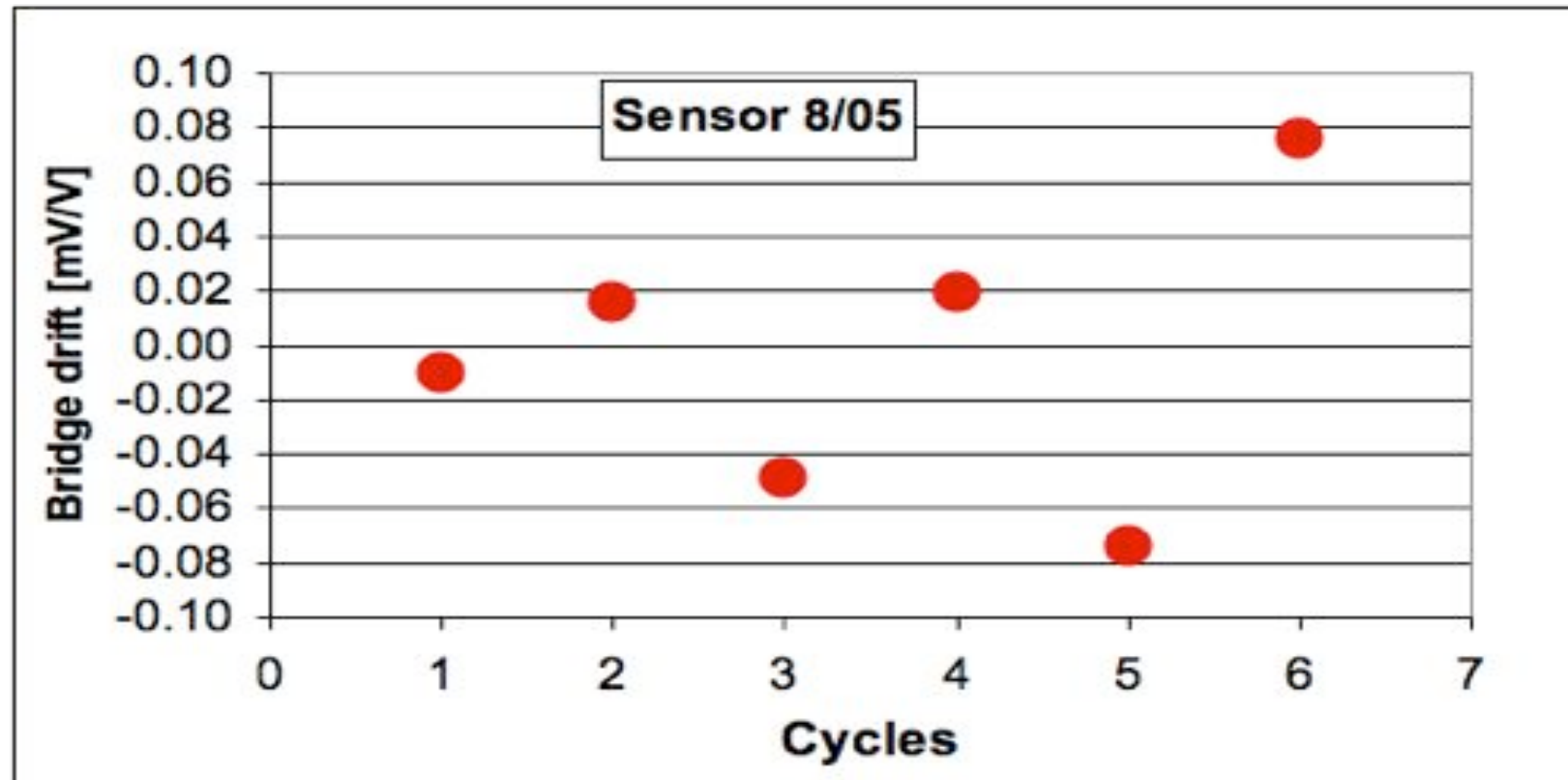
- Values affected by interactions with LTCC
- Offsets OK

4. Measured sensor response



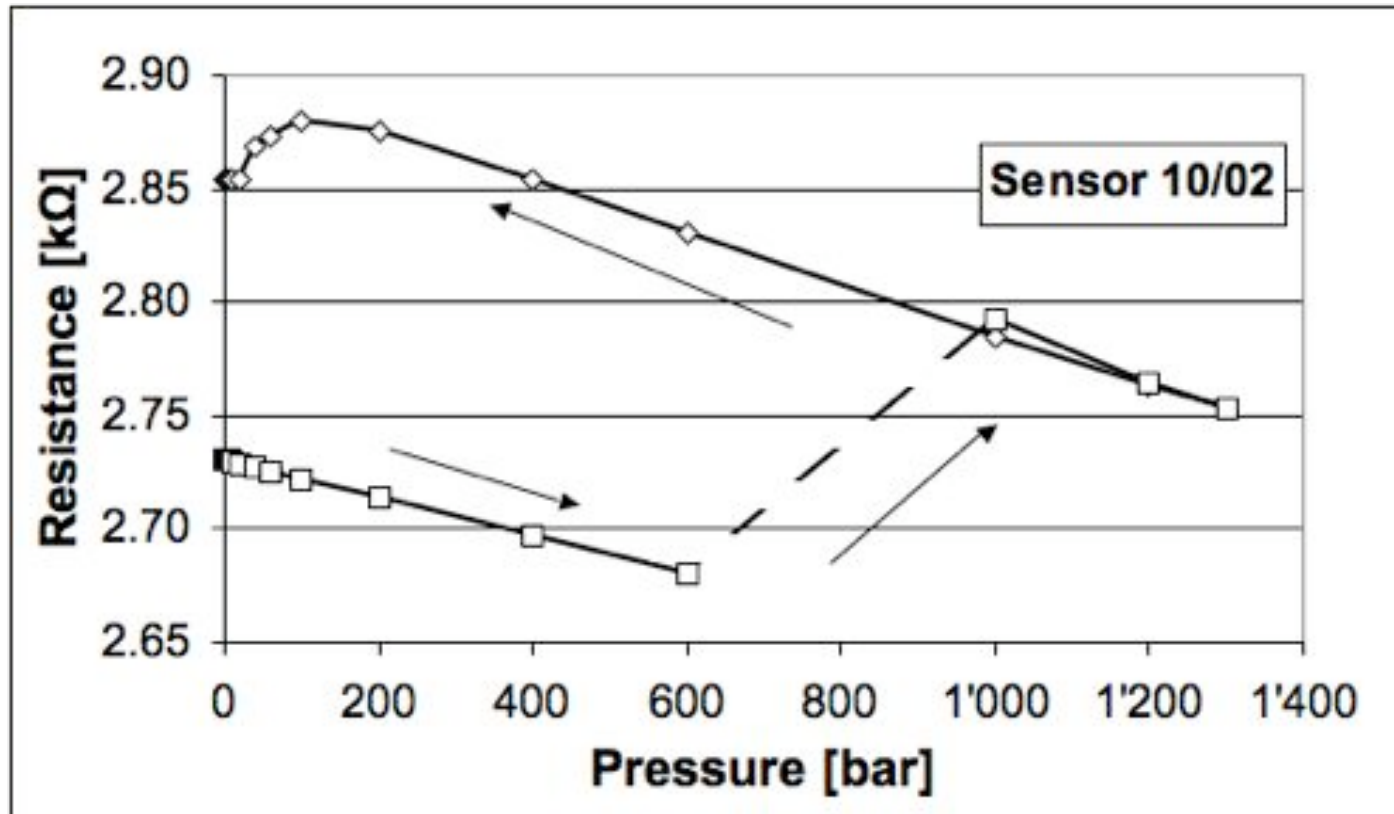
- Linear & hysteresis free behaviour up to 1'200 bar
- Response corresponds to expected value

4. Measured sensor drift



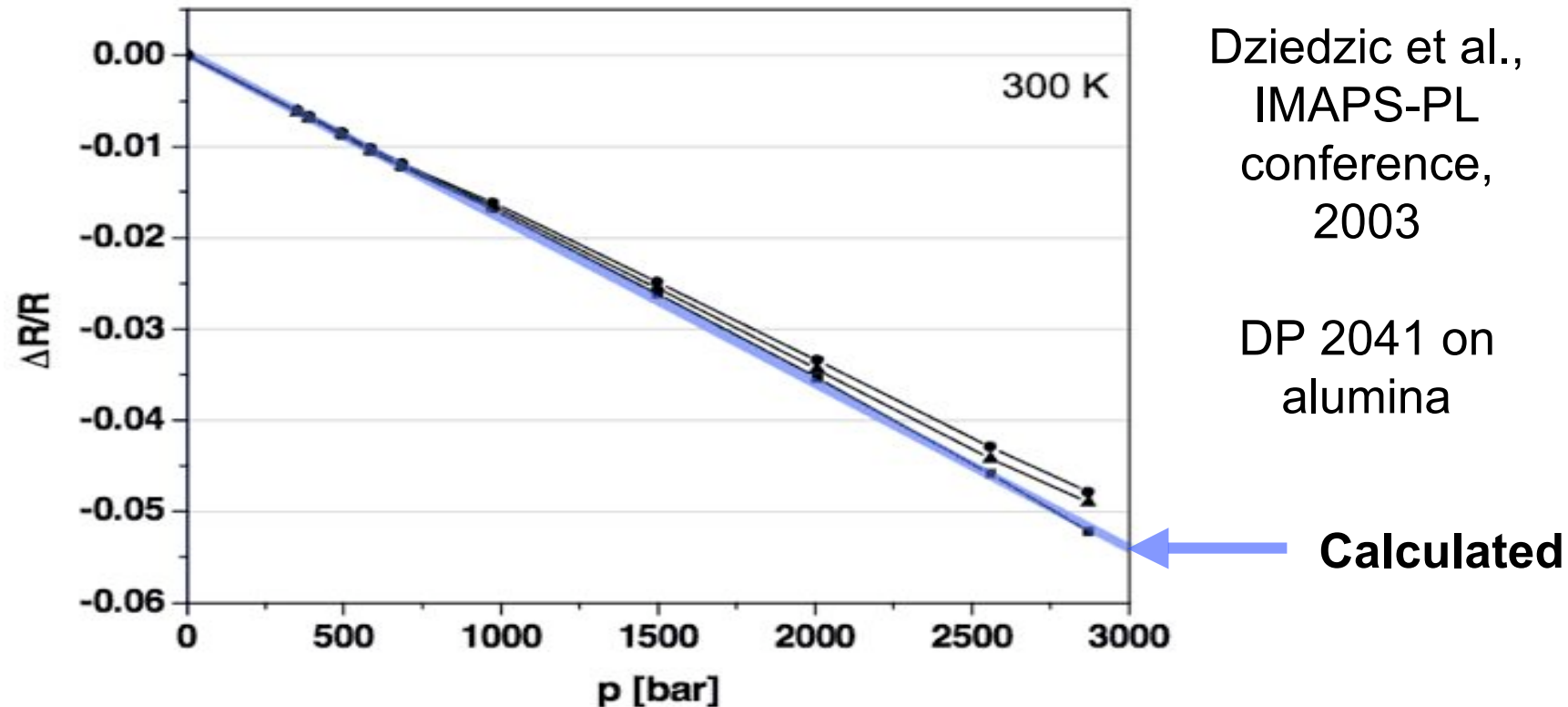
- Zero-pressure drift is low
- Drift probably thermal (sensor not compensated)

4. Limitations



- Problems with some sensors (sudden drift or death)
- Cause: voids or local stresses at feed-through ?

4. Comparison with other results



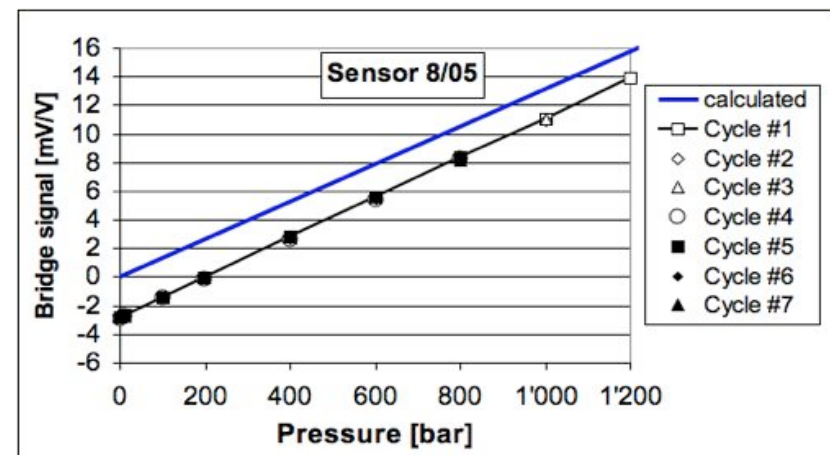
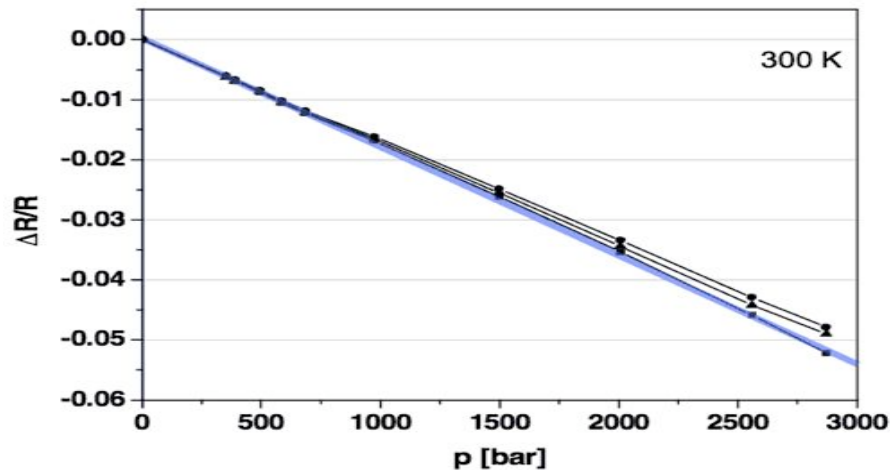
→ Very good match with published results on same resistors

5. Conclusions & outlook

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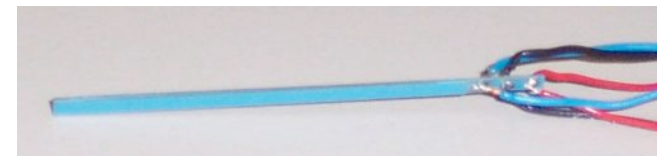
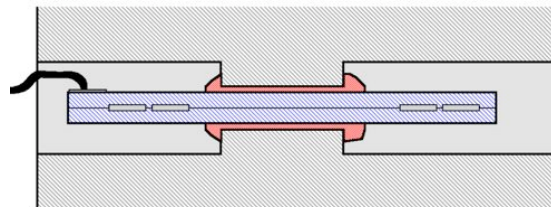
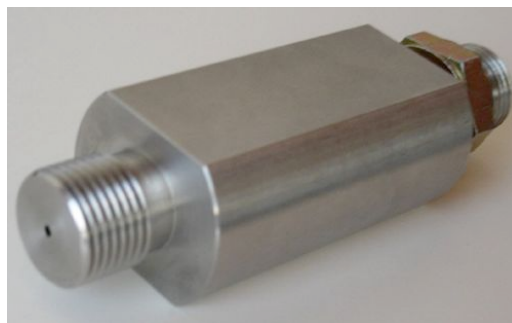
5. Conclusions

- Studied “hydrostatic” LTCC high pressure sensor
- Model for resistors under hydrostatic pressure
- Sensor successfully tested at > 1'000 bar
- Some quality issues
- High response agrees very well with predictions

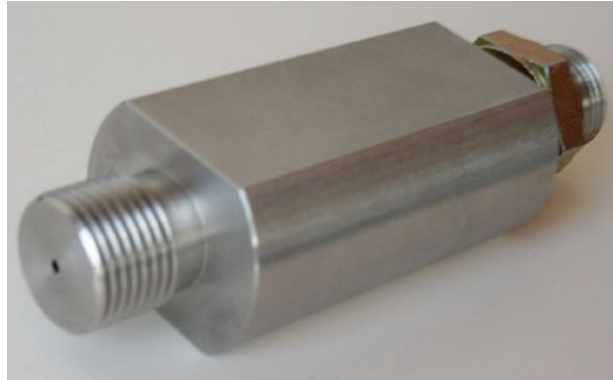


5. Outlook

- Characterise sources of failures under pressure
 - Bubbles / voids in LTCC structure ?
 - Stress gradients in feed-through ?
- Improve feed-through (epoxy → glass ?)
- Hydrostatic studies on other resistors
- Better characterisation of resistor materials



Merci



Thank you !

